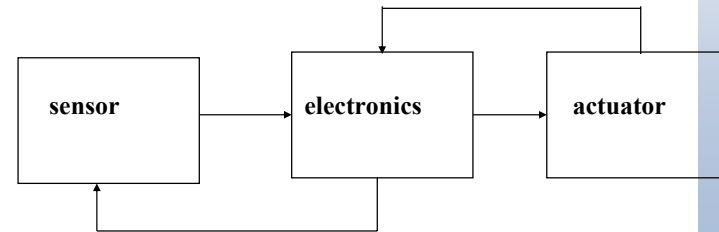


SYSTEM INTEGRATION

Dr. Bruce K. Gale
Fundamentals of Micromachining

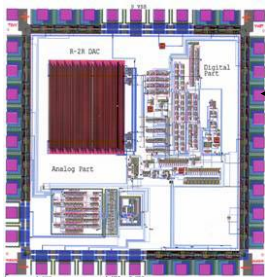
System Integration

- Interfacing of electronics with sensors/actuators
 - (decision making capability or intelligence)

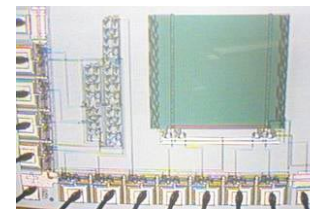
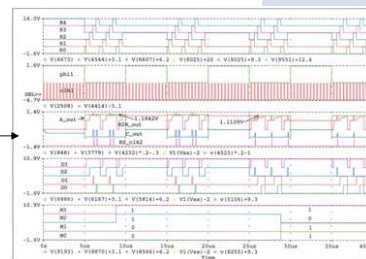


Monolithic Integration

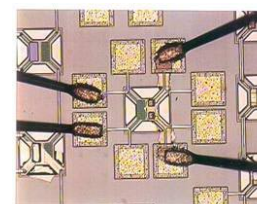
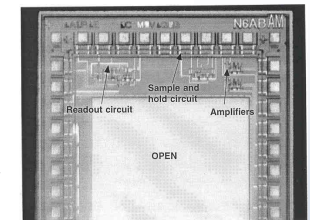
Integration of chemical, mechanical, biochemical or optical microsystems with electronics



← circuit design and simulation →

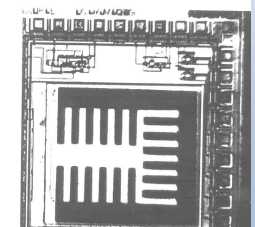


circuit fabrication at a foundry



Gas sensor

fabricated microsystem on a chip with circuits



Accelerometer

System Integration

- Pre-IC fabrication
- Co-IC fabrication
- Post-IC fabrication

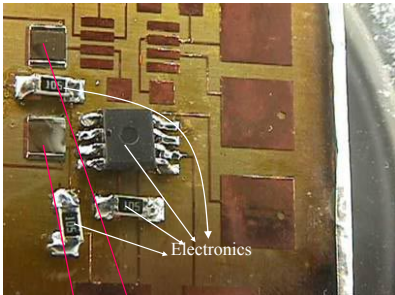
Post-IC fabrication requires:

- Low temperature < 450 C
- Benign chemical environment
- Benign radiation requirement

Summary of steps

- Circuit design and simulation
- CMOS circuit fabrication at foundry
- Co- and Post-IC MEMS fabrication
- System packaging

Hybrid or Modular Integration

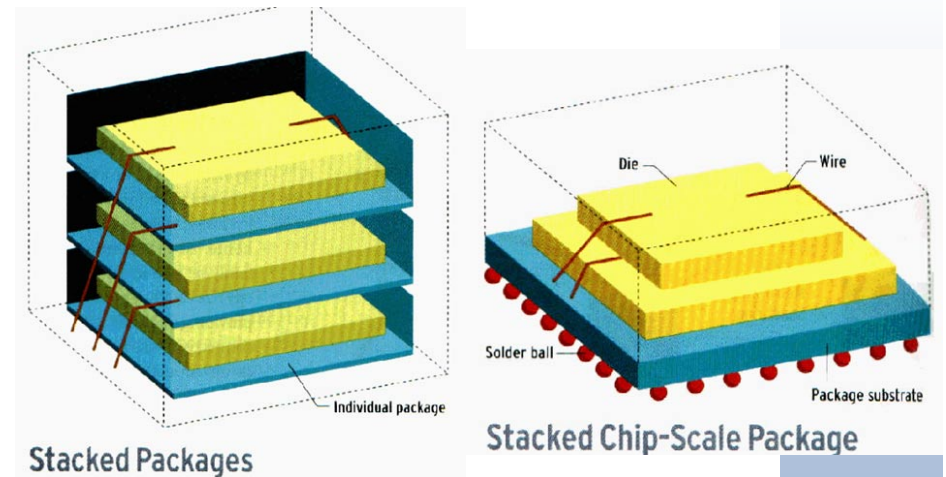


MEMS pressure sensor array



Micrograph of pressure sensor array

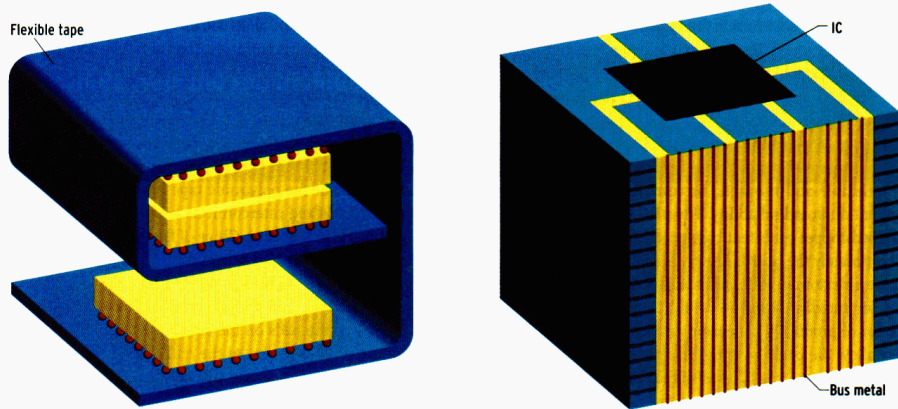
3-D Packages



Stacked Packages

Stacked Chip-Scale Package

3-D Packages



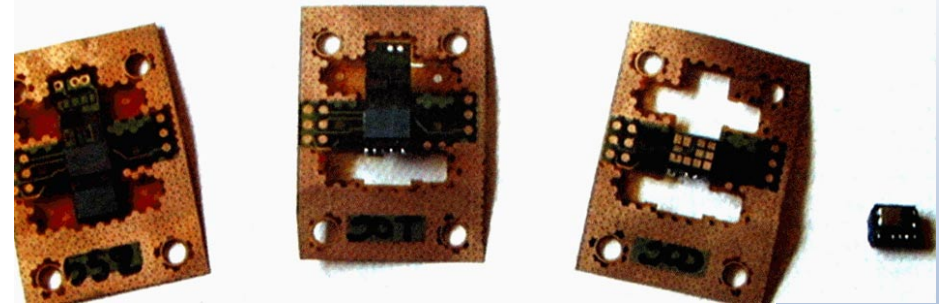
Folded Package

One of the newer ways for cramming capability into a small package starts with packaged chips on a flat polyimide tape. The flexible tape is then folded to yield a small footprint.

System-in-a-Cube

The densest package so far relies on a stack of epoxy layers in which are embedded different kinds of chips. Metal interconnects to the layers run along the sides of the stack.

Folded Packaging



Both passive and active components included in this hearing aid